

In the Claims

Please amend claims 21, 22, 23, 25, 31, 33 and 36 as indicated in the attached Claims Listing.

A complete Claims Listing showing all claims presently in the application and indicating the present status of each pending claim, is attached as required by 37 C.F.R. § 1.121(c).

In the Claims

Claims 1-19 (Cancelled).

20. (Withdrawn) Optical assembly having a plurality of optical elements, forming a projection objective or an illuminating system, wherein at least one optical element is connected to a structure dynamically decoupled from the optical assembly, as a result of which it is substantially dynamically decoupled from the remaining optical elements of the optical assembly.

21. (Withdrawn and Currently Amended) Optical assembly according to Claim [[1]] 20, wherein provided in a housing of the optical assembly is at least one opening through which said dynamically decoupled optical element can be connected to the structure dynamically decoupled from the optical assembly.

22. (Withdrawn and Currently Amended) Optical assembly according to Claim [[1 or 2]] 20, wherein sensors are provided for determining the position of said optical element relative to the housing or relative to the remaining optical elements of the optical assembly.

23. (Currently Amended) An apparatus, comprising[[,]]; an optical assembly and a feeder device; said optical assembly having a beam path and having a plurality of optical elements forming a projection objective or an illuminating system said feeder device being operable to interchangeably insert into the beam path and to remove from the beam path[[,]] at least one optical element of said plurality of optical elements, [[with]] said at least one optical element being substantially dynamically decoupled from the remaining ones of said plurality of optical elements of the optical assembly.

24. (Previously Amended) An apparatus according to Claim 23, wherein said optical assembly includes a housing having an opening adapted to the dimensions of said

at least one optical element, said at least one optical element being inserted into the beam path and removed from the beam path by way of said opening.

25. (Currently Amended) An apparatus according to Claim 23, wherein said feeder device is connected to a structure dynamically decoupled from the optical assembly.

26. (Previously Amended) An apparatus according to Claim 25, further comprising a lifting device, said at least one optical element being positioned and/or fixed in the beam path via said lifting device.

27. (Previously Amended) An apparatus according to Claim 26, wherein said lifting device is dynamically decoupled from the optical assembly and is connected to the structure dynamically decoupled from the optical assembly.

28. (Previously Amended) An apparatus according to Claim 23, wherein said apparatus further comprises a holding device which serves as a stop and/or for fixing said at least one optical element in the beam path.

29. (Previously Amended) An apparatus according to Claim 28, wherein for the purpose of fixing said at least one optical element in the beam path, said holding device is connected to one of said remaining ones of said plurality of optical elements.

30. (Previously Amended) An apparatus according to Claim 28, wherein said at least one optical element is fixed in the beam path by said holding device using magnetic forces.

31. (Currently Amended) An [optical] apparatus according to Claim 26, wherein spring elements are provided between said lifting device and said at least one optical element.

32. (Previously Amended) An apparatus according to Claim 26, wherein said feeder device and/or said lifting device are arranged outside the optical assembly.

33. (Withdrawn and Currently Amended) [Optical assembly] An apparatus according to Claim 23, wherein said dynamically decoupled optical element can be manipulated by means of actuators.

34. (Previously Amended) An apparatus according to Claim 23, wherein said at least one optical element comprises a diaphragm, in particular a revolving disc diaphragm.

35. (Previously Amended) An apparatus according to Claim 23, wherein said apparatus is used in a projection exposure machine for microlithography in the field of EUVL for producing semiconductor components.

36. (Currently Amended) A projection exposure machine for microlithography in the EUVL field for producing semiconductor components with the aid of an [optical] apparatus in accordance with Claim 23.